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April 30, 2004

To: Commissioner for Patents

P.O.Box 1450

Alexandria, VA 22313-1450

Fr: George O. Saile, Reg. No. 19,572

28 Davis Avenue

Poughkeepsie, N.Y. 12603

Subject:

| Serial No. 10/776,793 02/11/04 |

Indrajit Manna et al.

TRIGGERED SILICON CONTROLLED RECTIFIER FOR RF ESD PROTECTION

INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation
In An Application.

The following Patents and/or Publications are submitted to comply with the duty of disclosure under CFR 1.97-1.99 and 37 CFR 1.56.

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on May \checkmark , 2004.

Stephen B. Ackerman, Reg.# 37761

Signature/Date

- U.S. Patent Application Publication US 2003/0016479 A1 to Song, "Electrostatic Discharge (ESD) Protection Circuit of Silicon-Controlled Rectifier (SCR) Structure Operable at a Low Trigger Voltage," describes an ESD protection circuit having silicon-controlled rectifier structure that includes a PNP transistor and an NPN transistor.
- U.S. Patent 6,605,493 to Yu, "Silicon Controlled Rectifier ESD Structures with Trench Isolation," teaches about an SCR ESD protection device used with shallow trench isolation structures.
- U.S. Patent 6,580,184 to Song, "Electrostatic Discharge (ESD) Protection Circuit of Silicon-Controlled Rectifier (SCR) Structure Operable at a Low Trigger Voltage," illustrates an ESD protection circuit having a silicon-controlled rectifier structure.
- U.S. Patent 6,534,834 to Ashton et al., "Polysilicon Bounded Snapback Device," teaches about a snapback device that functions as a semiconductor protection circuit to prevent damage to integrated circuits resulting from events such as electrostatic discharage.

- U.S. Patent 6,610,262 to Peng et al., "Depletion Mode SCR for Low Capacitance ESD Input Protection," describes an ESD semiconductor protection with reduced input capacitance.
- U.S. Patent 5,453,384 to Chatterjee, "Method of Making a Silicon Controlled Rectifier Device for Electrostatic Discharge Protection," describes a silicon controlled rectifier structure that is provided for electrostatic discharge protection.
- U.S. Patent 5,159,518 to Roy, "Input Protection Circuit for CMOS Devices," details an input protection circuit that protects MOS semiconductor circuits from electrostatic discharge voltages and from developing circuit latchup.
- U.S. Patent 5,629,544 to Voldman et al., "Semiconductor Diode with Silicide Films and Trench Isolation," discusses a structure for improving device characteristics of protection diodes on chips having trench isolation and silicide contacts.

Voldman et al., "Electrostatic Discharge (ESD) Protection in Silicon-on-Insulator (SOI) CMOS Technology with Aluminum and Copper Interconnects in Advanced Microprocessor Semiconductor Chips," EOS/ESD Symposium 99-105, pp. 2A.6.1 to 2A.6.11, discusses the electrostatic discharge (ESD) robustness of silicon-on-insulator (SOI) high-pin-count high-performance semiconductor chips.

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Voldman et al., "Semiconductor Process and Structural Optimization of Shallow Trench Isolation-Defined and Polysilicon-Bound Source/Drain Diodes for ESD Networks," EOS/ESD Symposium 98-151, pp. 3A.1.1 to 3A.1.10, discusses the impact of MOSFET source/drain junction scaling on ESD robustness of shallow trench isolation (STI)-defined diode structures, ESD robustness improvements to STI-bound p+ diodes using germanium preamorphization and deep B11 implants, and polysilicon-bordered ESD networks.

Sharma et al., "An ESD Protection Scheme for Deep Submicron ULSI Circuits," 1995 Symposium on VLSI Technology Digest of Technical Papers, pp. 85-86, describes a scheme for on-chip protection of sub-micron ULSI circuits against ESD stress using low voltage zener-triggered SCR, and a zener-triggered thin gate oxide MOSFET.

Sincerely,

Stephen B. Ackerman,

Reg. No. 37761

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